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500.36904X00
Hayes

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MIURA, et al.

Serial No.: 09/254,939

Filed: March 17, 1999

For: METHOD OF FABRICATING SEMICONDUCTOR DEVICE
HAVING TRENCH ELEMENT SEPARATION STRUCTURE
(AS AMENDED)

Group: 2814

Examiner: A. Mai



AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

November 9, 2000

Sir:

In response to the Office Action mailed August 9, 2000,
please amend the above-identified application as follows:

IN THE SPECIFICATION

Please amend the specification as follows:

Page 8, line 4, after "or" insert --after--.

Page 20, line 13, delete "te" and insert --the--.

Page 21, line 2, delete "polycrystalline" and insert
--polycrystalline--;

line 18, delete "9" and insert --19--.

Page 27, line 24, delete "lithography" and insert
--lithography--.

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